

REMARKS

Pursuant to 35 U.S.C. 121, the Examiner is requesting restriction between the invention of Group I, namely claims 1-20 drawn to a device for positioning a brush of a wafer cleaning system, classified in class 15, subclass 88.3 and the invention of Group II, namely claims 21-22 drawn to a method of positioning a brush of a wafer cleaning system, classified in class 134, subclass 18.

Responsive thereto, the Applicants provisionally elect the claims of the Group I invention drawn to a device for positioning a brush of a wafer cleaning system, claims 1-20, for prosecution on the merits. This election is made without traverse.

An action on the merits is now in order and such is respectfully requested.

The Director is authorized to charge any payment required under 37 CFR 1.16 and any patent application processing fees under 37 CFR 1.17, which are associated with this paper, or credit any overpayment to Deposit Account No. 04-1679.

Respectfully submitted,

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